

AUTHOR INDEX

- Akdemir, Eyup, 159
 Allen, Mark, 59
- Bahr, David, 53
 Basak, Nupur, 193
 Beadling, Les, 181
 Belarni, Aissa, 141
 Borenstein, Jeffrey T., 27
 Braunlin, Bill, 181
 Brida, Sebastiano, 217
 Bryce, George, 13
 Burda, R., 175
 Burggraf, Jurgen, 133
- Cakmak, Erkan, 127, 133
 Cao, X.A., 163
 Chintapatla, Shravan, 97
 Churaman, Wayne, 41
 Coccetti, Fabio, 141
 Coppeta, Jonathan, 225
 Cortes, D., 175
 Currano, Luke, 41
- Daniel, Rostislav, 115
 Desmarres, Jean Michel, 217
 Dragoi, Viorel, 127, 133
 Du Bois, Bert, 13
- Ebel, Joshua, 109
 Ecke, Ramona, 65
 Economy, James, 239
 El-Gamal, Mourad, 47
- Famouri, P., 163
 Farrell, R., 163
 Feldman, Leonard C., 103
 Fujisawa, Takashi, 187
 Funakubo, Hiroshi, 187
 Fung, Daisy, 159
- Gardner, Bob, 133
 Gaspar, Joao, 211
 Gee, Danny, 41
- Gieschke, Pascal, 201
 Gouldstone, Andrew, 147
 Griffin, James, 193
 Gruenzig, Sven, 19, 65
- Harris, Gary L., 193
 Hata, Seiichi, 83
 Held, Jochen, 211
 Henry, Jim, 133
 Hensel, J.P., 163
 Higo, Yakichi, 71
 Hmelo, Anthony B., 103
- Ichikawa, Naoki, 121
 Ide, Yuki, 83
 Ignat, Michel T., 217
 Ishikawa, Mutsuo, 187
 Ishiyama, Chiemi, 71
 Ivanov, Dentcho V., 181
- James, Teena, 181
 Ji, Chang-Hyeon, 59
- Kabulski, A., 163, 175
 Kano, Seisuke, 121
 Keckes, Jozef, 115
 Kim, Jae Hun, 147
 Kim, Yoonkap, 53
 Korach, Chad S., 147
 Korakakis, D., 163, 169, 175
 Kuchibhatla, Sridhar, 169
 Kurosawa, Minoru, 187
 Kwak, Kwangsik, 77
- Lafontan, Xavier, 217
 Lange, Peter, 19, 65
 LaVan, David A., 89
 Lay, Sabine, 217
 Lemke, Benjamin, 201
 Li, Deyu, 103
 Li, Xuan, 239
 Lunardi, Leda M., 97

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Index

[More information](#)

- Malhaire, Christophe, 217
 Maloney, John, 133, 225
 Marengo, Norman, 19, 65
 Martin, Jack, 3
 Martinschitz, Klaus, 115
 Mason, Keith, 133
 Matsumoto, Sohei, 121
 McBride, John, 233
 Mertens, Robert, 13
 Mittendorfer, Gerald, 127
 Mitterer, Christian, 115
 Morita, Takeshi, 187
 Mukdadi, O.M., 175
 Murauer, Franz, 127
 Muth, John F., 97
- Nabki, Frederic, 47
- Otsu, Masaaki, 77, 83
- Pabo, Eric, 127, 133
 Pagán, V.R., 163, 175
 Papaioannou, George, 141
 Paul, Oliver, 201, 211
 Plana, Robert, 141
 Pons, Patrick, 141
 Prabhakar, Sairam, 47
 Prakash, Shaurya, 159
 Puers, Robert, 13
- Reid, James R., 153
 Reinert, Wolfgang, 65
 Rodak, L E., 169
 Roussel d'Herbey, Francine, 217
- Sakurai, Junpei, 83
 Schmidt, Marek E., 211
 Sebastian Mannoor, Manu, 181
 Seguineau, Cedric, 217
- Semperowitsch, Thilo, 19
 Shafer, Richard, 59
 Shibata, Akinobu, 71
 Sone, Masato, 71
 Sosnov, Eugene, 159
 Spearing, S. Mark, 233
 Sridhar, Manoj, 103
 Sridharan, Sid, 133
 Stoffels, Steve, 13
- Takashima, Kazuki, 77, 83
 Tilmans, Harrie A., 13
- Utsugi, Satoru, 187
- Van Hoof, Rita, 13
 Vasilyev, Vladimir, 153
 Vengallatore, Srikar, 47
 Vitarelli, Michael, 159
- Warnat, Stephan, 19, 65
 Webster, Richard T., 153
 Wise, Ken, 193
 Witvrouw, Ann, 13
- Xiang, Yu, 89
 Xu, Dongyan, 103
 Xu, Wenjun, 59
- Yamada, Tomoaki, 187
 Yasui, Shintaro, 187
 Yeldandi, S., 163
 Yoder, Karl, 225
 Yunus, Esa, 233
- Zaghoul, Usama, 141
 Zakar, Eugene, 41
 Zeng, Hansong, 109
 Zhao, Yi, 109

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Editors: Srikar Vengallatore, Jörg Bagdahn, Norman F. Sheppard and S. Mark Spearing

Index

[More information](#)

SUBJECT INDEX

- actuator, 41, 233
- adhesion, 71
- Al, 211
- alloy, 127
- amorphous, 83

- biological, 193
- biomedical, 27, 109, 181
- bonding, 127

- C, 59
- chemical
 - reaction, 89
 - synthesis, 89, 239
 - vapor deposition (CVD)
 - (chemical reaction), 13
 - (deposition), 65, 233

- devices, 121, 181
- dielectric, 141
- ductility, 217

- elastic properties, 97, 147, 217
- electrodeposition, 53, 59
- electronic material, 193

- fatigue, 77, 225
- ferroelectric, 187
- fluidics, 103, 121, 159
- fracture, 71

- Ga, 53

- hydrothermal, 187

- internal friction, 47

- laser, 83
- lubricant, 239

- metal, 115, 127
- metalorganic deposition, 65
- microelectro-mechanical (MEMS),
 - 3, 13, 19, 27, 41, 47, 53,
 - 71, 77, 89, 97, 109, 121,
 - 133, 141, 147, 153, 159,
 - 163, 169, 175, 181, 193,
 - 201, 211, 217, 225, 233
- microelectronics, 133, 187
- microstructure, 19, 59

- nanoscale, 103, 159
- nanostructure, 109
- nitride, 141

- packaging, 19, 65
- piezoelectric, 41, 163, 175

- Raman spectroscopy, 169
- reactive ion etching, 13

- screen printing, 133
- sensor, 3, 175, 201
- stress/strain relationship, 153, 201, 211
- surface chemistry, 3

- thermal stresses, 97
- thin film, 47, 77, 83, 115, 147, 153, 225
- III-V, 163, 169
- tissue, 27
- tribology, 239

- water, 103

- x-ray diffraction (XRD), 115